Special Issue

State-of-the-Art Fabrication, Characterization and Manipulation Techniques for Nanomaterials and Structures

Message from the Guest Editors

Nanomaterials and nanostructures have attracted significant attention in the past two decades, motivated by their growing importance in a wide range of applications, including catalysis, nanoelectronics, nano-optics, energy storage, and biological sensors. Accordingly, this Special Issue seeks to showcase research papers, communications, and review articles that focus on recent advances in experimental techniques and applications, as well as theoretical/computational modeling of state-of-the-art nanostructure/heterostructure fabrication techniques, advanced material characterization methods, and strategies for tailoring and manipulating material properties using physical and chemical means. These include but are not limited to self-assembly, top-down and bottom-up growth methods, 2D heterostructure fabrications, advanced scanning probe microscopy and electron microscopy characterizations, chemical functionalization, strong light–matter interactions, and nanostructure-enabled devices.

Guest Editors

Dr. Ziwei Wang

Applied Physics Program, Northwestern University, Evanston, IL 60208, USA

Dr. Xiaolong Liu

Department of Physics, University of Notre Dame, Notre Dame, IN 46556, USA

Deadline for manuscript submissions

closed (15 June 2023)

Micromachines

an Open Access Journal by MDPI

Impact Factor 3.0
CiteScore 6.0
Indexed in PubMed

mdpi.com/si/125692

Micromachines
Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland
Tel: +41 61 683 77 34
micromachines@mdpi.com

mdpi.com/journal/micromachines

Micromachines

an Open Access Journal by MDPI

Impact Factor 3.0
CiteScore 6.0
Indexed in PubMed

mdpi.com/journal/micromachines

About the Journal

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

Editor-in-Chief

Prof. Dr. Ai-Qun Liu
1. Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China
2. School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

Author Benefits

High Visibility:

indexed within Scopus, SCIE (Web of Science), PubMed, PMC, Ei Compendex, dblp, and other databases.

Journal Rank:

JCR - Q2 (Instruments and Instrumentation) / CiteScore - Q1 (Mechanical Engineering)

Rapid Publication:

manuscripts are peer-reviewed and a first decision is provided to authors approximately 17.2 days after submission; acceptance to publication is undertaken in 1.9 days (median values for papers published in this journal in the first half of 2025).

MDPI